

Search Notes

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10/655,942

Examiner

Paul D. Kim

Applicant(s)/Patent under
Reexamination

HASEGAWA, NAOYA

Art Unit

3729

SEARCHED

Class	Subclass	Date	Examiner
29	603.07 603.08 603.11- 603.16	2/22/2006	PK
	603.18		
360	324.11		
	324.12		
	324.2		
216	22,39 40		
427	127 128		
451	5, 41		
360	121 122		
	126 317	↓	

**SEARCH NOTES
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
Reviewed Parent Application 09/905,330 (US PAT. 6,751,073)'	2/22/2006	PK
Text Search EAT/NPL (IEEE)	2/23/2006	PK

INTERFERENCE SEARCHED

Class	Subclass	Date	Examiner